

**Amendments to the Claims:**

**Listing of Claims:**

Claims 1-74 (canceled)

- 5     75. (currently amended) A multi-chip structure comprising:
- a first chip comprising a first pad comprising a first gold layer, a metal layer
- over said first gold layer, a copper layer over said metal layer, and a nickel layer over
- said copper layer;
- a second chip; and
- 10           a tin-containing material connecting said first pad to said second chip.

Claims 76-77 (canceled)

78. (currently amended) The structure of Claim 75, wherein said first pad further
- 15     comprises a second gold layer over said nickel layer.

79. (previously presented) The structure of Claim 75, wherein said tin-containing material further comprises copper.

- 20     80. (currently amended) The structure of Claim 75 further comprising a wire wirebonded to a second pad of said first chip.

81. (previously presented) The structure of Claim 75, wherein said tin-containing material further comprises lead.

- 25     82. (previously presented) The structure of Claim 75, wherein said tin-containing material further comprises silver.

83. (currently amended) A multi-chip structure, comprising:

a first chip comprising:

a semiconductor substrate comprising multiple MOS devices,

a metallization structure over said semiconductor substrate,

5 a passivation layer over said metallization structure, an opening in said passivation layer exposing a top surface of a first pad of said metallization structure, and

a second pad connected to said top surface of said first pad, wherein said second pad comprising a copper layer and a nickel layer over said copper layer;

10 a second chip over said first chip; and

a tin-containing material on said nickel layer, wherein said tin-containing material connects ~~connecting~~ said second pad to said second chip.

15 Claims 84-85 (canceled)

86. (previously presented) The structure of Claim 83, wherein said second pad further comprises a gold layer over said nickel layer.

20 87. (previously presented) The structure of Claim 83, wherein said tin-containing material further comprises copper.

88. (previously presented) The structure of Claim 83, wherein said second pad further comprises a gold layer under said copper layer.

25 89. (previously presented) The structure of Claim 83, wherein said second pad comprises an electroplated metal.

Claim 90 (canceled)

91. (currently amended) The structure of Claim 83 further comprising a wire wirebonded to a third pad of said first chip.

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92. (previously presented) The structure of Claim 83, wherein said tin-containing material further comprises lead.

93. (previously presented) The structure of Claim 83, wherein said tin-containing material  
10 further comprises silver.

94. (currently amended) A multi-chip structure, comprising:

a first chip comprising:

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a semiconductor substrate comprising multiple MOS devices,  
a metallization structure over said semiconductor substrate,  
a passivation layer over said metallization structure, an opening in said  
passivation layer exposing a first pad of said metallization structure,  
a trace over said passivation layer, and  
a second pad on said trace, wherein said second pad is connected to said  
20 first pad through said trace, wherein said second pad comprises a copper layer  
and a nickel layer over said copper layer;  
a second chip over said first chip; and  
a tin-containing material connecting said second pad to said second chip.

25 Claims 95-96 (canceled)

97. (previously presented) The structure of Claim 94, wherein said second pad further comprises a gold layer over said nickel layer.

98. (previously presented) The structure of Claim 94, wherein said tin-containing material further comprises copper.

5    99. (previously presented) The structure of Claim 94, wherein said tin-containing material further comprises lead.

100. (previously presented) The structure of Claim 94, wherein said tin-containing material further comprises silver.

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101. (previously presented) The structure of Claim 94 further comprising a wire wirebonded to a third pad of said first chip.

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102. (currently amended) The structure of Claim 75, wherein said tin-containing material covers a top surface and a sidewall of said first pad.

103. (previously presented) The structure of Claim 83, wherein said tin-containing material covers a top surface and a sidewall of said second pad.

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104. (previously presented) The structure of Claim 83, wherein said passivation layer comprises silicon nitride.

105. (previously presented) The structure of Claim 94, wherein said tin-containing material covers a top surface and a sidewall of said second pad.

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106. (previously presented) The structure of Claim 94, wherein said trace comprises a gold layer having a thickness of greater than 1 micron.

107. (previously presented) The structure of Claim 94, wherein said passivation layer comprises silicon nitride.

5 108. (previously presented) The structure of Claim 75, wherein said metal layer comprises titanium.

109. (previously presented) The structure of Claim 108, wherein said metal layer further comprises tungsten.

10 110. (previously presented) The structure of Claim 75, wherein said metal layer comprises chromium.

Claim 111 (canceled)

15 112. (currently amended) The structure of Claim 75, 111, wherein said first gold layer has a thickness of greater than 1 micron.

20 113. (currently amended) The structure of Claim 75, 111 wherein said first pad further comprises ~~comprising~~ a titanium-containing layer under said first gold layer.

114. (previously presented) The structure of Claim 113, wherein said titanium-containing layer further comprises tungsten.

25 115. (currently amended) The structure of Claim 75, wherein said first pad comprises an electroplated metal.

116. (previously presented) The structure of Claim 75, wherein said nickel layer is on said copper layer.

117. (previously presented) The structure of Claim 75, wherein said tin-containing material is on said nickel layer.

5 118. (previously presented) The structure of Claim 83, wherein said passivation layer has a thickness of greater than 0.35 microns.

119. (previously presented) The structure of Claim 83, wherein said first pad comprises aluminum.

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120. (previously presented) The structure of Claim 83, wherein said first pad comprises electroplated copper.

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121. (previously presented) The structure of Claim 83, wherein said semiconductor substrate comprises silicon.

122. (previously presented) The structure of Claim 88, wherein said gold layer has a thickness of greater than 1 micron.

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123. (previously presented) The structure of Claim 88, wherein said second pad further comprises a titanium-containing layer under said gold layer.

124. (previously presented) The structure of Claim 123, wherein said titanium-containing layer comprises tungsten.

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125. (previously presented) The structure of Claim 83, wherein said nickel layer is on said copper layer.

126. (previously presented) The structure of Claim 83, wherein said second pad comprises a titanium-containing layer under said copper layer.

127. (previously presented) The structure of Claim 126, wherein said titanium-containing  
5 layer comprises tungsten.

128. (previously presented) The structure of Claim 83, wherein said second pad comprises a chromium-containing layer under said copper layer.

10 Claim 129 (canceled)

130. (previously presented) The structure of Claim 94, wherein said passivation layer has a thickness of greater than 0.35 microns.

15 131. (previously presented) The structure of Claim 94, wherein said first pad comprises aluminum.

132. (previously presented) The structure of Claim 94, wherein said first pad comprises electroplated copper.

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133. (previously presented) The structure of Claim 94, wherein said semiconductor substrate comprises silicon.

134. (previously presented) The structure of Claim 94, wherein said trace comprises a  
25 titanium-containing layer and a gold layer over said titanium-containing layer.

135. (previously presented) The structure of Claim 134, wherein said titanium-containing layer comprises tungsten.

136. (previously presented) The structure of Claim 94, wherein said trace comprises gold.

137. (previously presented) The structure of Claim 94 further comprising a polymer layer  
5 between said trace and said passivation layer.

138. (previously presented) The structure of Claim 137, wherein said polymer layer comprises polyimide.

10 139. (previously presented) The structure of Claim 137, wherein said polymer layer comprises benzocyclobutene.

140. (previously presented) The structure of Claim 94 further comprising a polymer layer on said trace.  
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141. (previously presented) The structure of Claim 140, wherein said polymer layer comprises polyimide.

142. (previously presented) The structure of Claim 140, wherein said polymer layer  
20 comprises benzocyclobutene.

143. (previously presented) The structure of Claim 94 further comprising a polymer layer and first and second patterned metal layers over said passivation layer, wherein said polymer layer is between said first and second patterned metal layers, said first and  
25 second patterned metal layers comprises said trace.

144. (previously presented) The structure of Claim 143, wherein said polymer layer comprises polyimide.



145. (previously presented) The structure of Claim 143, wherein said polymer layer comprises benzocyclobutene.

5 146. (previously presented) The structure of Claim 94, wherein said trace comprises an electroplated metal.

147. (previously presented) The structure of Claim 94, wherein said nickel layer is on said copper layer.

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Claims 148-151 (canceled)

152. (previously presented) The structure of Claim 94, wherein said second pad comprises a titanium-containing layer under said copper layer.

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153. (previously presented) The structure of Claim 152, wherein said titanium-containing layer comprises tungsten.

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154. (previously presented) The structure of Claim 94, wherein said second pad comprises a chromium-containing layer under said copper layer.

155. (previously presented) The structure of Claim 94, wherein said tin-containing material is on said nickel layer.

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156. (previously presented) The structure of Claim 94, wherein said trace has a sidewall separated from said passivation layer.

157. (previously presented) The structure of Claim 101, wherein said third pad comprises

a gold layer.

158. (previously presented) The structure of Claim 157, wherein said gold layer has a thickness of greater than 1 micron.

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159. (currently amended) The structure of Claim 157, wherein said third pad further comprises ~~has a~~ titanium-containing layer under said gold layer.

160. (previously presented) The structure of Claim 159, wherein said titanium-containing  
10 layer comprises tungsten.

161. (previously presented) The structure of Claim 101, wherein said third pad has a same material as said trace.

15 162. (new) The structure of Claim 80, wherein said second pad comprises a second gold layer.

163. (new) The structure of Claim 162, wherein said second gold layer has a thickness of greater than 1 micron.

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164. (new) The structure of Claim 162, wherein said second pad further comprises a titanium-containing layer under said second gold layer.

165. (new) The structure of Claim 164, wherein said titanium-containing layer comprises  
25 tungsten.

166. (new) The structure of Claim 91, wherein said third pad comprises a gold layer.

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167. (new) The structure of Claim 162, wherein said gold layer has a thickness of greater than 1 micron.

168. (new) The structure of Claim 162, wherein said third pad further comprises a  
5 titanium-containing layer under said gold layer.

169. (new) The structure of Claim 164, wherein said titanium-containing layer comprises tungsten.